Mechanical properties of Ropaque hollow nanoparticles

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Supporting information

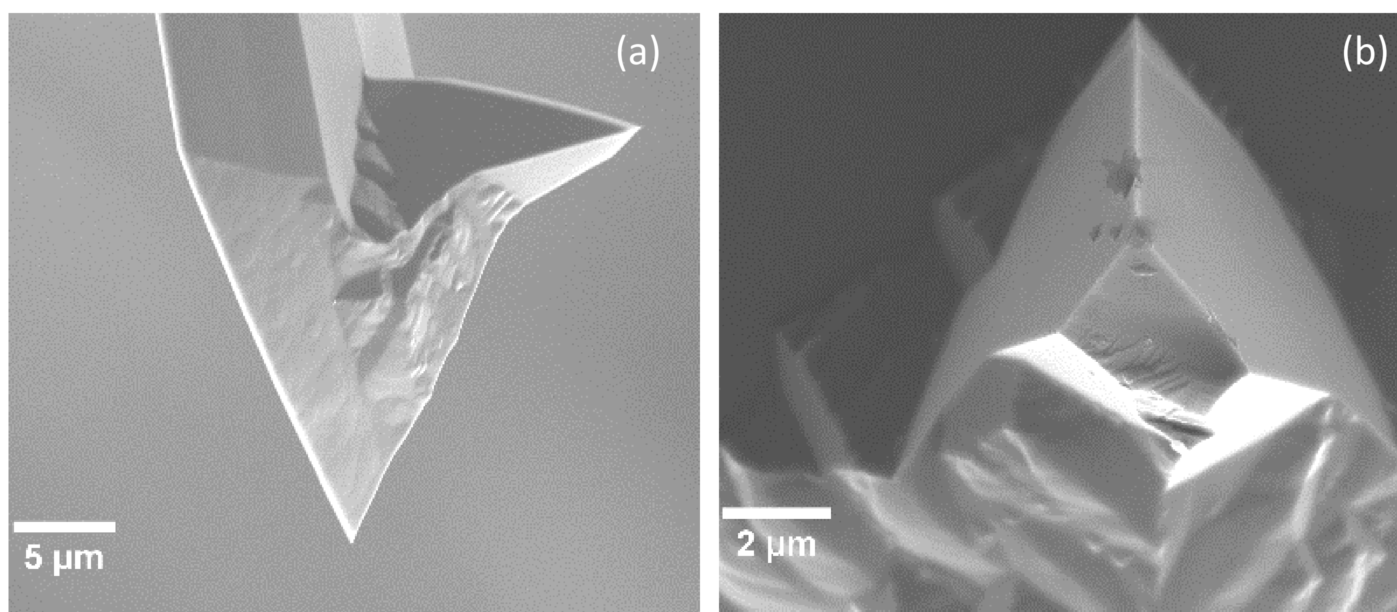

Figure S1 SEM micrographs of an AFM tip (a) before use and (b) after repeated force measurements at high loads in hard contact with silicon wafer.

After the tip was driven at high loads through the Ropaque particles and reached hard contact with the silicon wafer substrate, evidence of tip blunting was seen in the subsequent AFM image. Figure S1 shows SEM images of the AFM tip before use and after performing repeated high force loading in hard contact (see Figure S1(b)).